

FORM PTO-1449 (Modified) LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)	ATTY. DOCKET NO. JEV/KAR:1016.2018	SERIAL NO.
	APPLICANT Ron A. Peters et al.	
	FILING DATE July 8, 2003	GROUP

REFERENCE DESIGNATION
U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>DN</i>	AA	3,185,927	5/25/1965	Margulis et al.			
	AB	3,333,274	7/25/1967	Forcier			
	AC	3,405,361	10/8/1968	Kattner et al.			
	AD	3,710,251	1/9/1973	Hagge et al.			
	AE	4,115,736	9/19/1978	Tracy			
	AF	4,383,178	5/10/1983	Shibata et al.			
	AG	4,694,245	9/15/1987	Frommes			
	AH	4,731,577	3/15/1988	Logan			
	AI	4,755,746	7/5/1988	Mallory et al.			
	AJ	4,757,255	7/12/1988	Margozzi			
	AK	4,758,785	7/19/1988	Rath			
	AL	4,771,234	9/13/1988	Cook et al.			
	AM	4,845,426	7/4/1989	Nolan et al.			
	AN	4,856,904	8/15/1989	Akagawa			
	AO	4,884,026	11/28/1989	Hayakawa et al.			
	AP	5,077,523	12/31/1991	Blanz			
	AQ	5,084,671	1/28/1992	Miyata et al.			
	AR	5,220,277	6/15/1993	Reitinger			
	AS	5,266,889	11/30/1993	Harwood et al.			
	AT	5,345,170	9/6/1994	Schwindt et al.			
	AU	5,457,398	10/10/1995	Schwindt et al.			
	AV	5,963,027	10/5/1999	Peters			
	AW	6,002,263	12/14/1999	Peters et al.			
	AX	6,252,392	06/26/2001	Peters			
	AY	6,288,557	09/11/2001	Peters et al.			
	AZ	6,362,636	03/26/2002	Peters et al.			
<i>DN</i>	BA	6,489,789	12/03/2002	Peters et al.			

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
<i>DN</i>	BB	1-209380	8/1989	Japan	—	—		
	BC	2-220453	9/1990	Japan	—	—		
	BD	201205	12/1986	European Patent Office	—	—		
	BE	3114466	3/1982	Germany	—	—		
	BF	2-022837	1/1990	Japan	—	—		
<i>DN</i>	BG	4-000732	1/1992	Japan	—	—		

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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

ON	BH	"Model TPO3000 Series Thermochuck® Systems," four-page product note, Temptronic Corporation, Newton, MA (May 1992 or earlier)
	BI	"Application Note 1 Controlled Environment Enclosure," two-page application note, "Temptronic Corporation, Newton, MA (May 1992 or earlier)
	BJ	"Cross Section Signatone S-1240," one-page sketch prepared by Signatone counsel, Signatone, San Jose, CA (February 1988 or earlier per Signatone)
	BK	"S-1240," two-page product note, Signatone, San Jose, CA (February 1988 or earlier per Signatone counsel)
	BL	Y. Yamamoto, "A Compact Self-Shielding Prober ...," IEEE Trans., Inst. and Meas., Vol. 38, pp 1088-1093, 1989
	BM	Temptronic's "Guarded" Chuck, one-page note describing guarding system of Temptronic Corporation of Newton, MA, dated 11/15/89
	BN	Beck & Tomann, "Chip Tester," IBM Technical Disclosure Bulletin, p. 4819 (January 1985)
	BO	Article by William Knauer entitled "Fixturing for Low-Current/Low Voltage Parametric Testing," appearing in Evaluation Engineering, (1990) pp. 150-153
	BP	Hewlett-Packard, "Application Note 356-HP 4142B Modular DC Source/Monitor Practical Applications," (Nov. 1987) pp. 1-4
	BQ	Hewlett-Packard, H-P Model 4284A Precision LCR Meter, Operation Manual (December 1991) pp. 2-1, 6-9 and 6-15
	BR	Cascade Microtech, "Advanced On-Wafer Device Characterization Using the Summit 10500, (December 1992)
	BS	Micromanipulator Company, Inc., "Test Station Accessories," 1983. (month unavailable)
	BT	Micromanipulator Company, Inc., "Model 8000 Test Station," 1986. (month unavailable)
	BU	Micromanipulator Company, Inc., "Model 8000 Test Station," 1988. (month unavailable)
	BV	Micromanipulator Company, Inc., "Probing Stations and Accessories," 1995, pp. 1-12.
	BW	Photograph of Micromanipulator Probe Station, 1994.
ON	BX	Applebay, Harry F., Deposition transcript (pp. 61-67) with Exhibits 581 A, B, C describing Flexion AP-1 probe station sold in 1987.

EXAMINER

Jimmy Nguyen

DATE CONSIDERED

5/11/04

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.